

Inventor(s): Scheiberlich

Appl. No.: 09

827,350

Series Code ↑

Serial No. ↑

Filed: April 6, 2001

Hon. Commissioner of Patents

Washington, D.C. 20231

Group Art U 2851

Examiner: Hung Nguyen

Atty. Dkt. P 279263

P-0177.010-US

M#

Client Ref

Appl. Title: Lithographic apparatus, device  
manufacturing method, and device  
manufactured thereby

Sir:

**REPLY/AMENDMENT/LETTER**

Date: April 23, 2003

This is a reply/amendment/letter in the above-identified application and includes the herewith attachment of same date and subject which is incorporated hereinto by reference and the signature below is treated as the signature to the attachment in absence of a signature thereto.

**FEE REQUIREMENTS FOR CLAIMS AS AMENDED**

1. Small Entity claim

For B &amp; C

A. ☒ NOT madeSee **Required**  
**Separate Paper**  
(Pat-256)B. ☐ WithdrawnC. ☐ made herewithD. ☐ made previously

Claims remaining after amendment	Highest number previously paid for	Present Extra	Large/Small Entity	Additional Fee	Fee Code Lg/Sm
2. Total Effective Claims	17	**minus 20	0	x \$18/\$9 = + \$0	103/203
3. Independent Claims	4	***minus 3	1	x \$84/\$42 = + \$84	102/202
4. If amendment enters proper multiple dependent claim(s) into this application for first time (leave blank if this is a reissue application) ..... add				+ \$280/\$140 = + \$0	104/204
5. Original due Date: February 28, 2003		<input type="checkbox"/> NONE			
6. Petition is hereby made to extend the original due date to cover the date this response is filed for which the requisite fee is attached		(1 mo) \$110/\$55 = (2 mos) \$410/\$205 = (3 mos) \$930/\$465 = (4 mos) \$1,450/\$725 = (5 mos) \$1,970/\$985 =	+ \$410		115/215 116/216 117/217 118/218 128/228
7. Enter any previous extension fee paid since above original due date and subtract			- \$0		
8. Extension Fee			+ \$410		
9. If Terminal Disclaimer attached, add Rule 20(d) official fee			+ \$110/\$55	+ \$0	148/248
10. If IDS attached requires Official Fee under Rule 97 (c), ..... add			+ \$180	+ \$0	126
or if Rule 97(d) Request ..... add			+ \$180		126
11. After-Final Request Fee per rules 129(a) and 17(r)			+ \$750/370	+ \$0	146/246
12. No. of additional inventions for examination per Rule 129(b)			x \$750/375 ea	+ \$0	149/249
13. Request for Continued Examination (RCE)			+ \$750/375	+ \$0	1179/1279
14. Petition fee for				+ \$0	
15. TOTAL FEE =			<b>\$494</b>		
16. *If the entry in this space is less than entry in next space, the "Present Extra" result is "0".					
17. **If the "Highest number previously paid for" in this space is less than 20, write "20" in this space.					
18. ***If the "Highest number previously paid for" in this space is less than 3, write "3" in this space.					

**PLEASE CHARGE  
OUR DEP. ACCT**

04/24/2003 HUUONG1 00000044 033975 09827350

Our Deposit Account No. 03-3975)

(Our Order No. 81468 279263

C#

M#

02 FC:1252

410-00 CH

CHARGE STATEMENT The Commissioner is hereby authorized to charge any fee specifically authorized hereafter, or any missing or insufficient fee(s) filed, or asserted to be filed, or which should have been filed herewith or concerning any paper filed hereafter, and which may be required under Rules 16-18 (missing or insufficiencies only) now or hereafter relative to this application and the resulting Official Document under Rule 20, or credit any overpayment, to our Accounting/Order Nos. shown above, for which purpose a duplicate copy of this sheet is attached.

This CHARGE STATEMENT does not authorize charge of the issue fee until/unless an issue fee transmittal sheet is filed.

Query: Is appeal deadline now? If so, file Notice of Appeals separately.

Pillsbury Winthrop LLP  
Intellectual Property Group

By Atty: Robert C. Perez

Reg. No. 39,328

P.O. Box 10500

McLean, VA 22102

Tel: (703) 905-2000

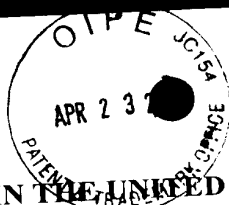
Sig:

Fax: (703) 905-2500

Tel: (703) 905-2159

Atty/Sec: RP/ml

**NOTE: File this cover sheet in duplicate with PTO receipt (PAT-103A) and attachments**



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION OF  
SCHEIBERLICH et al.

Appln. No.: 09/827,350

Filed: April 6, 2001

Title: LITHOGRAPHIC APPARATUS, DEVICE MANUFACTURING METHOD, AND  
DEVICE MANUFACTURED THEREBY

Confirmation No.: 2993

Group Art Unit: 2851

Examiner: H. NGUYEN

#6/a  
4-28-03  
JH  
(ext. fee on  
trans. sheet)

April 23, 2003

\* \* \* \* \*

AMENDMENT

Hon. Commissioner of Patents  
Washington, D.C. 20231

Sir:

In response to the Office Action dated November 29, 2002, please amend the above-identified application as follows:

IN THE SPECIFICATION:

Page 9, delete the whole paragraph starting in line 6 and replace it with the following new paragraph:

The beam PB subsequently intercepts the mask MA, which is held on a mask table MT. Having traversed the mask MA, the beam PB passes through the lens PL, which focuses the beam PB onto a target portion C of the substrate W. With the aid of the second positioning means (and interferometric measuring means IF), the substrate table WT can be moved accurately, e.g., so as to position different target portions C in the path of the beam PB using wafer alignment marks P1, P2. Similarly, the first positioning means can be used to accurately position the mask MA using mask alignment marks M1, M2 with respect to the path of the beam PB, e.g., after mechanical retrieval of the mask MA from a mask library, or during a scan. In general, movement of the object tables MT, WT will be realized with the